

Title (en)
DETECTING DEFECTS ON A WAFER

Title (de)
ERKENNUNG VON DEFECTEN AUF EINEM WAFER

Title (fr)
DETECTION DES DÉFAUTS SUR UNE TRANCHE

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Application
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Abstract (en)
[origin: WO2010093733A2] Methods and systems for detecting defects on a wafer are provided.

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Citation (search report)
• [I] US 2009037134 A1 20090205 - KULKARNI ASHOK [US], et al
• [A] US 2004246476 A1 20041209 - BEVIS CHRISTOPHER F [US], et al
• See references of WO 2010093733A2

Designated contracting state (EPC)
AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO PL PT RO SE SI SK SM TR

DOCDB simple family (publication)
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JP 5570530 B2 20140813; KR 101674698 B1 20161109; KR 20110124303 A 20111116; SG 173586 A1 20110929

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